

INFORMATION DISCLOSURE
CITATION

ATTY. DOCKET NO.

SERIAL NO.

249-245

Unknown

APPLICANT

TOMONARI et al.

(Use several sheets if necessary)

FILING DATE

GROUP

January 24, 2002

2834

 J1000 U.S. Pat.
 10/053576
 01/24/02

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	5,058,856	10/1991	GORDON et al.			
	5,069,419	12/1991	JERMAN			
	5,271,597	12/1993	JERMAN			
	5,059,133	10/1991	HIKAMI et al.			
	5,870,007	2/1999	CARR et al.			
	5,920,417	7/1999	JOHNSON			
	6,044,646	4/2000	SILVERBROOK			
	6,114,794	9/2000	DHULER et al.			
	1,258,368	3/1918	SMITH			
	4,115,750	9/1978	HANSEN et al.			
	6,087,638	7/2000	SILVERBROOK			
	6,124,663	9/2000	HAAKE et al.			

FOREIGN PATENT DOCUMENTS

DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
9-88805	3/1997	JAPAN			
10-173306	6/1998	JAPAN			

OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.)

	"Silicon Microvalves for Gas Flow Control" Phillip W. Barth, Ph.D. Hewlett-Packard Laboratoriespp 276-279 The 8 th International Conference on Solid-State Sensors and Actuators, and Eurosensors IX. Stockholm, Sweden, June 25-29, 1995
	"Electrically-Activated, Micromachined Diaphragm Valves" Hal Jerman IC Sensors Milpitas, CA 95035 pp 363-367

Examiner*

Date Considered

*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.

Form PTO-FB-A820 (Also PTO-1449)